

Electrospun α -Si using Liquid Silane/Polymer Inks

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Fukuoka, Japan

CNSE

NDSU
Center for Nanoscale
Science and Engineering





NDSU Old Main



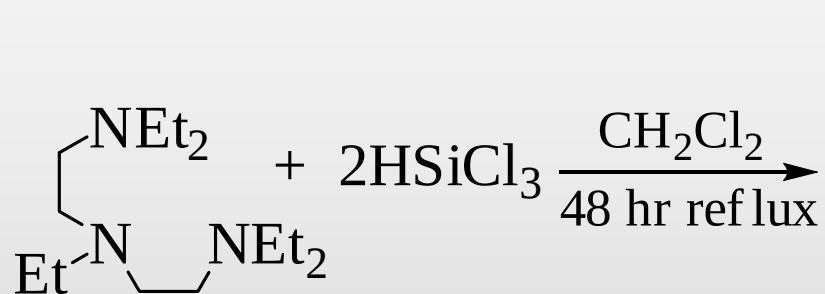
Research 2 – Home of NDSU-CNSE



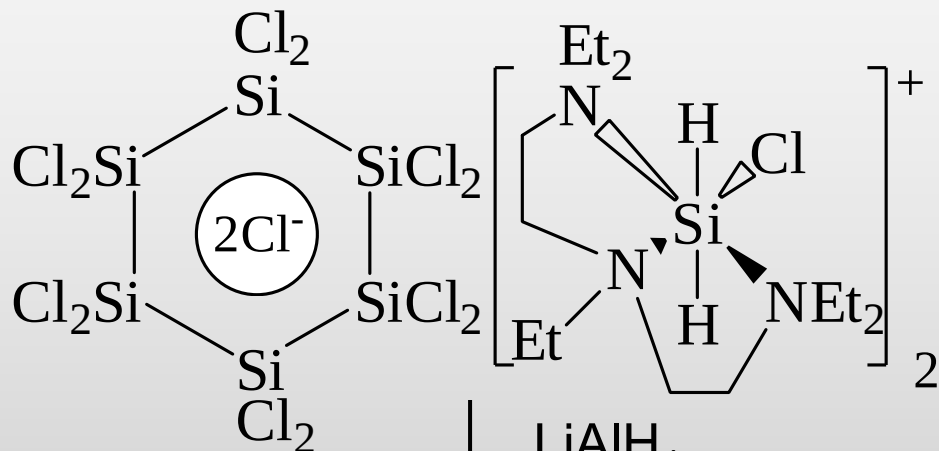
My 2nd home at NDSU

Cyclohexasilane Si₆H₁₂ Chemisty

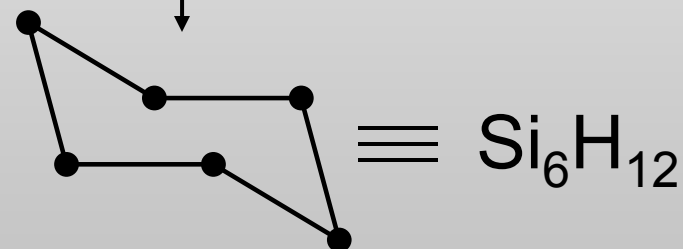
Amine-promoted disproportionation and redistribution: Si-Si bond formation



PEDETA + trichlorosilane



LiAlH₄
reduction



bp. ~ 80 °C/1.3Pa
mp. ~18 °C
ρ 0.97 g/mL



Philip Boudjouk



pyrophoric,
translucent liquid

P. Boudjouk et al.

J. Am. Chem. Soc. **2001**, 123, 8117-8



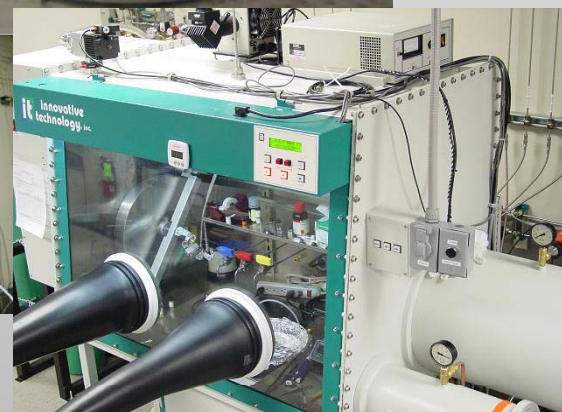
Si_6H_{12} Production at NDSU

- Scaleup to 10 g/week
- 2 kg/day facility envisioned
- Discussions with several manufacturers of fine chemicals for the semiconductor industry ongoing



3L reactor

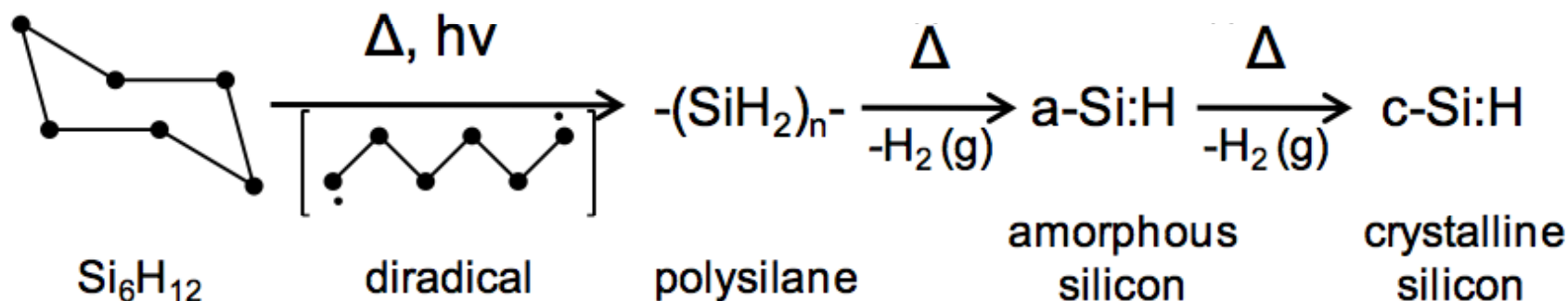
Si_6H_{12}
Distillation



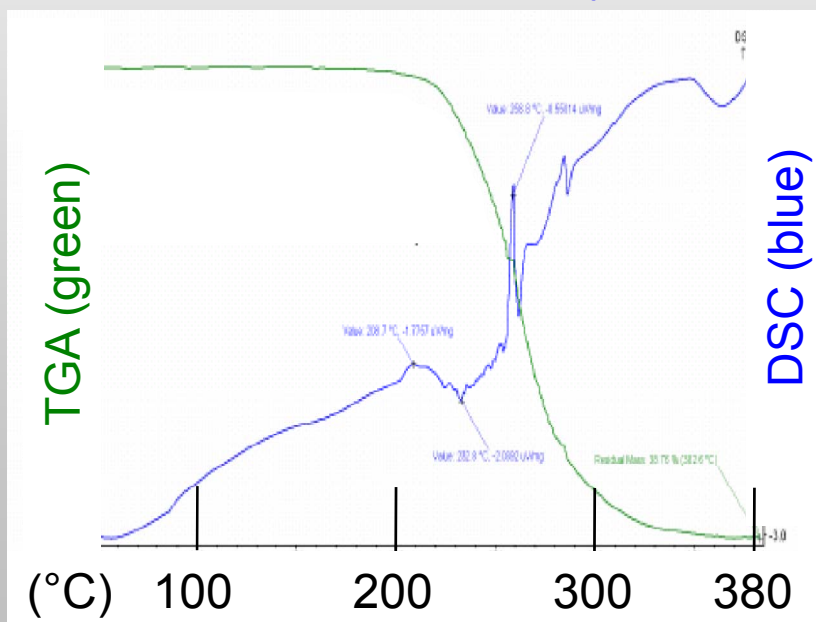
✧ Dr. Xuliang Dai



Si₆H₁₂ Precursor to Si-based Electronic Materials

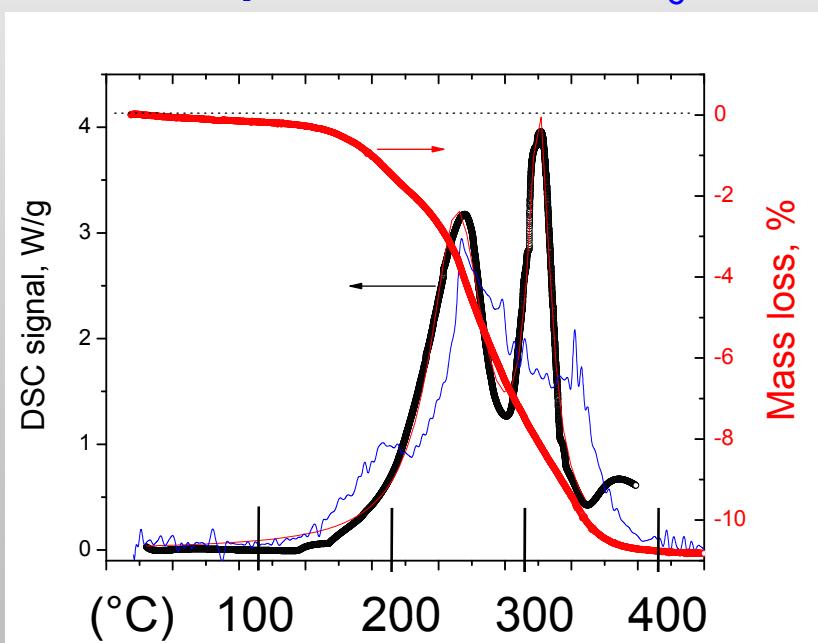


Thermal Stability



Isothermal TGA at 100 °C shows
 no weight change after 12 h

Thermolytic Behavior of Si₆LSM



Results similar to Shimoda et al.
Nature, **2006**, 440, 783-6.



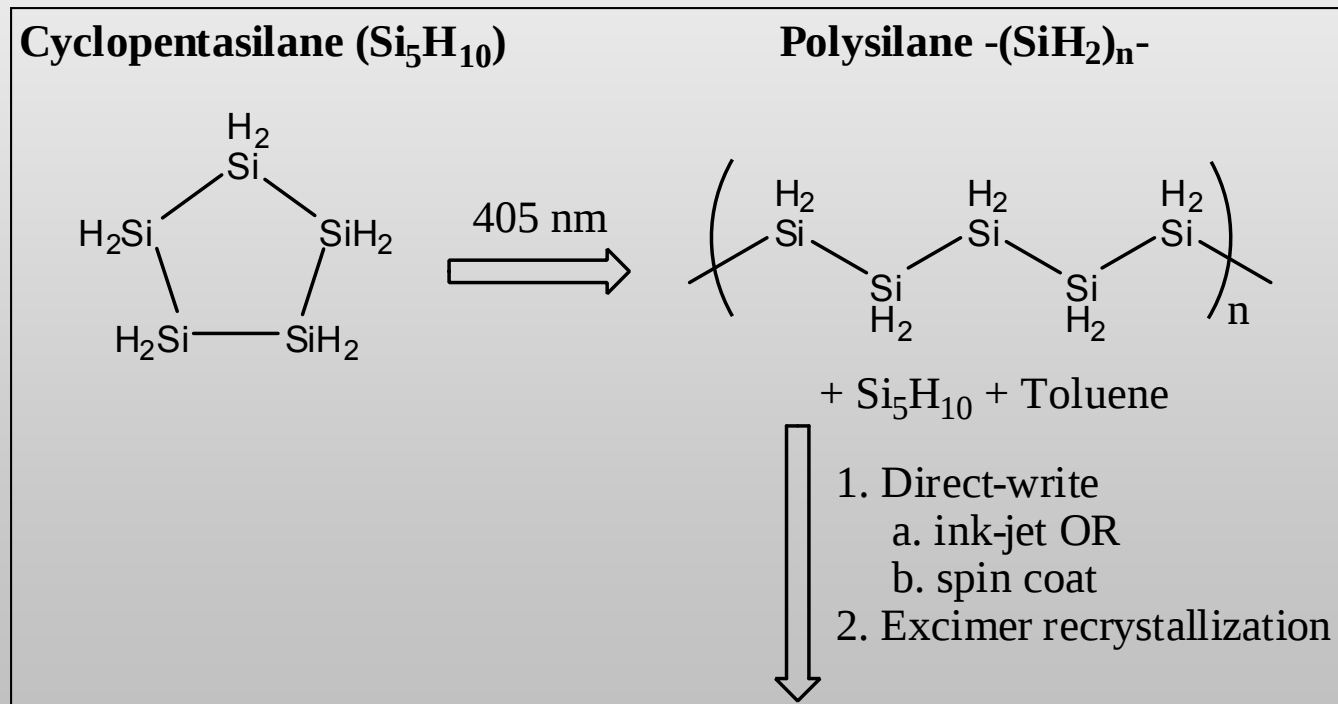
Initial Approach - Reproduce Seiko-Epson/JSR

Si₆LSM Ink Formulation and Method

10 mL laser-treated Si₆H₁₂ + 10 mL Si₆H₁₂ + 130 mL toluene

Spin coat

Thermal treatment (e.g., 40 min ramp to 350 °C / 20 min soak)



Recipe according to Shimoda et al. *Nature*, **2006**, 440, 783-6.

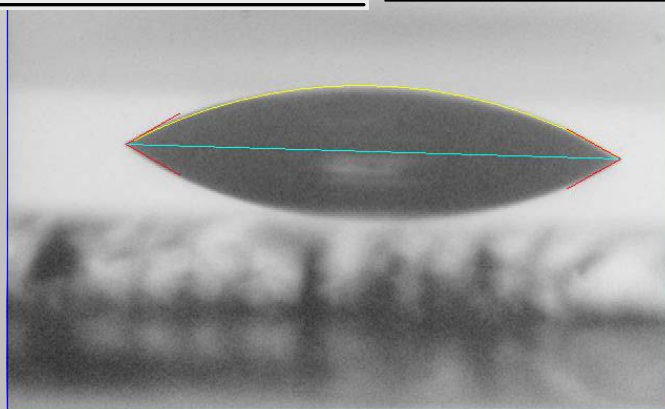
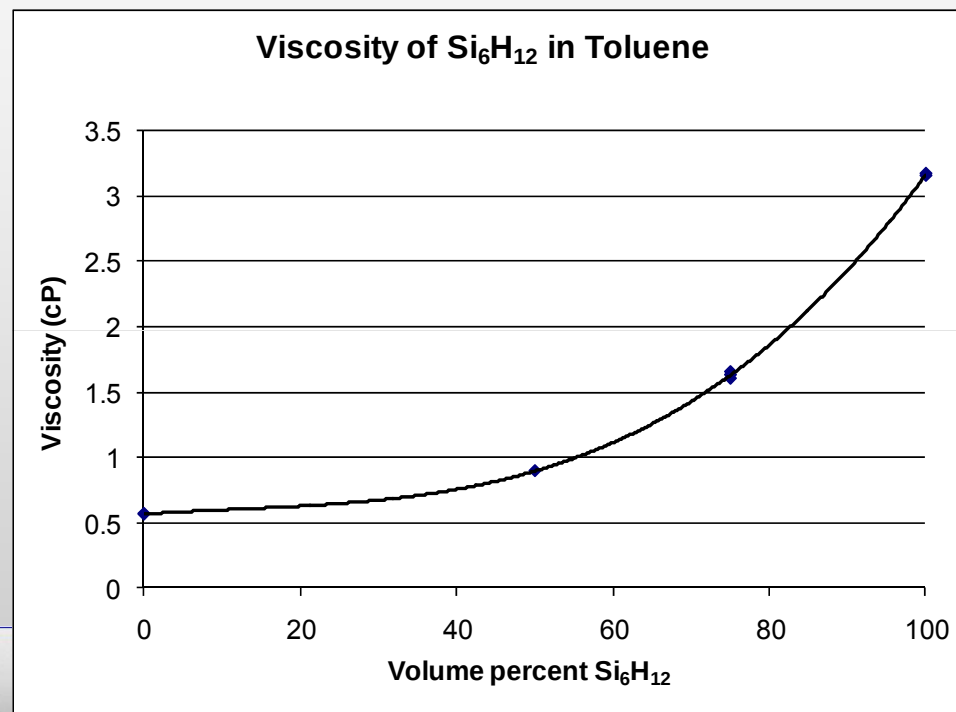


Characteristics of Si_6H_{12} and Si_6LSMs

Contact Angle

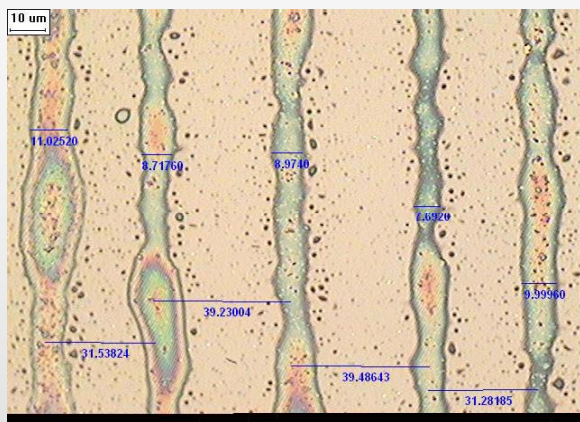
Substrate and Treatment [a]	Liquid (μL)	Contact angle ($^\circ$)
Glass (std)	10 μL Si_6H_{12}	25.3 ± 1.4
Glass (Pirahna)	10 μL Si_6H_{12}	19.2 ± 1.7
Si wafer (HF)	10 μL Si_6H_{12}	18.6 ± 1.7
Stainless (std)	10 μL Si_6H_{12}	13.7 ± 1.4
Glass (std & HMDS)	10 μL Si_6H_{12}	30.0
Glass (std)	2 μL Si_6H_{12}	26.3
Glass (std)	2 μL Si_6LSM	3.8

Viscosity



Liquid Silane Precursors to Printed Silicon

After UV

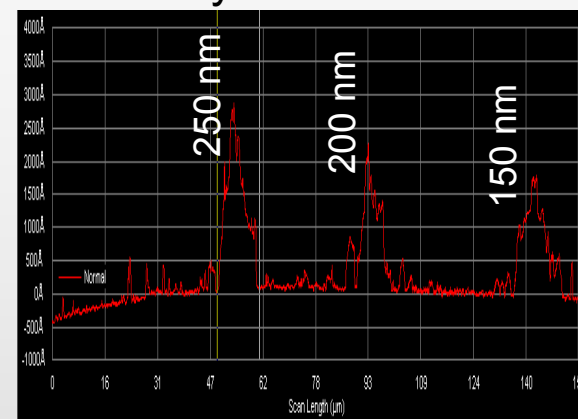


50 X mag

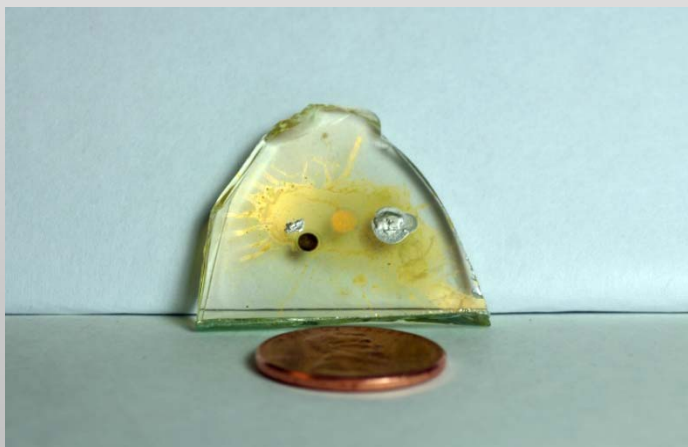
After UV + 350 °C



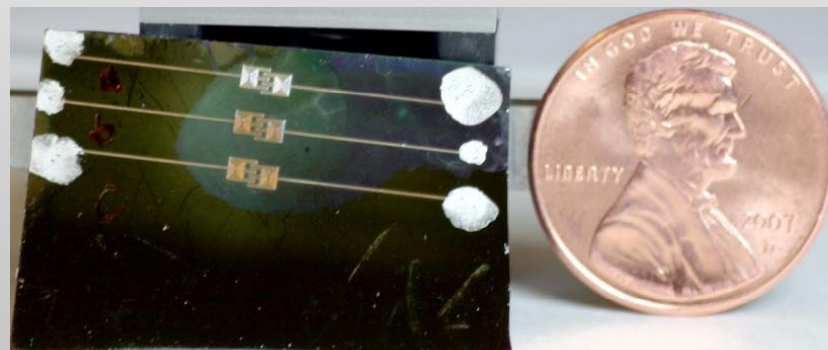
Stylus Profile



First Diode



First Transistor



Film thickness < 200 nm

Preliminary Studies: Limited to $T < 400\text{ }^{\circ}\text{C}$; Focused Mainly on Low-Temperature Dopants

NDSU-CNSE Si₆ers *J. Non-Cryst. Solids*, **2008**, 354, 2623-2626

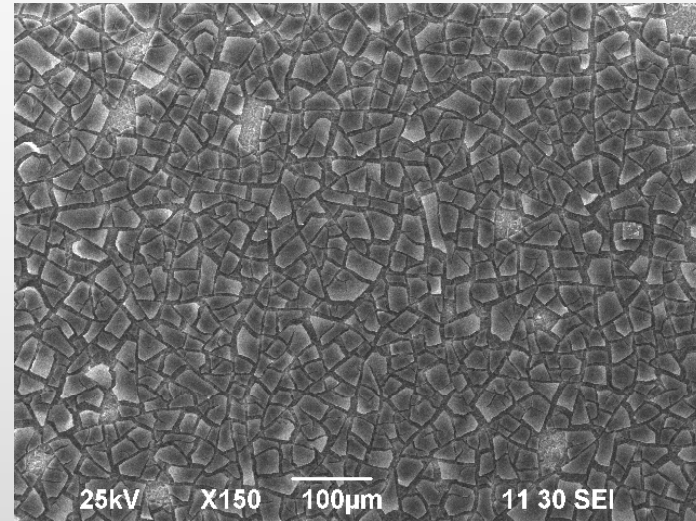
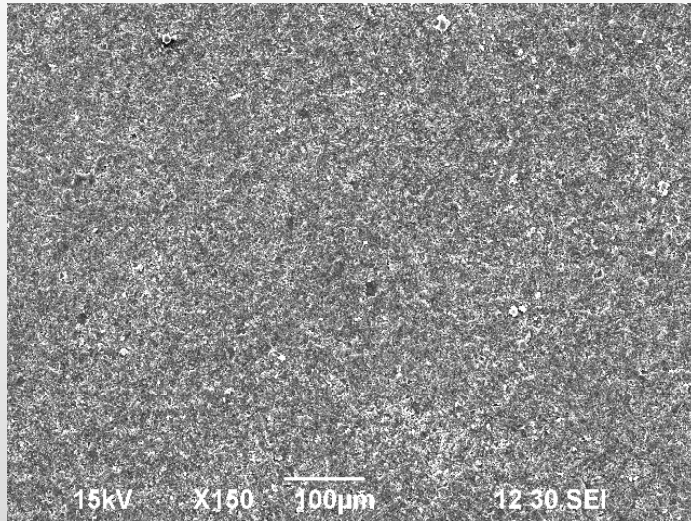


Printed Silicon – Thicker Films Crack

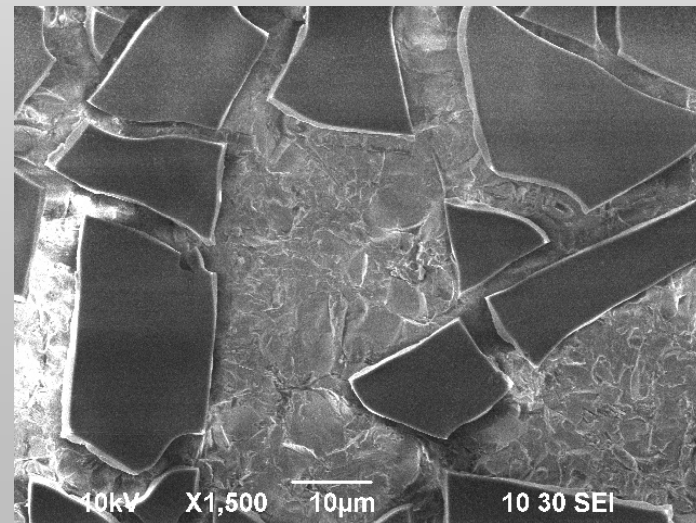
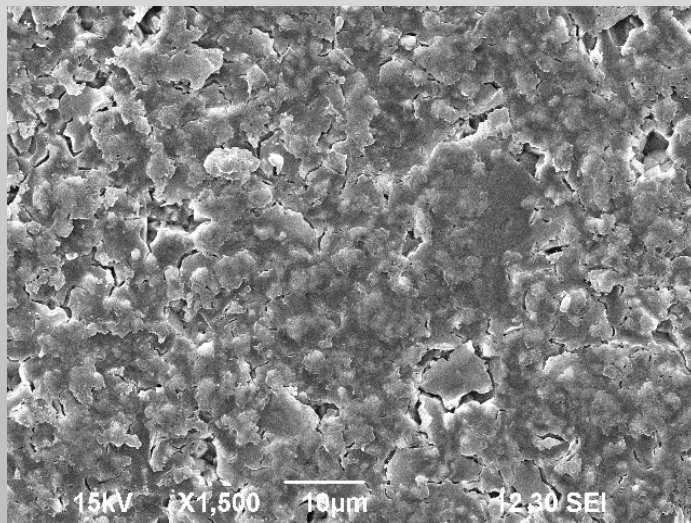
~1 μm

~3 μm

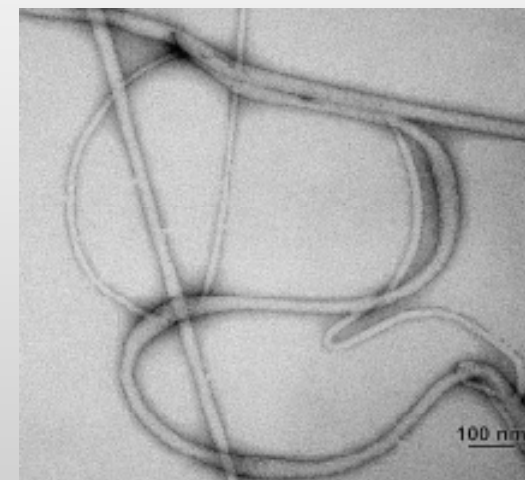
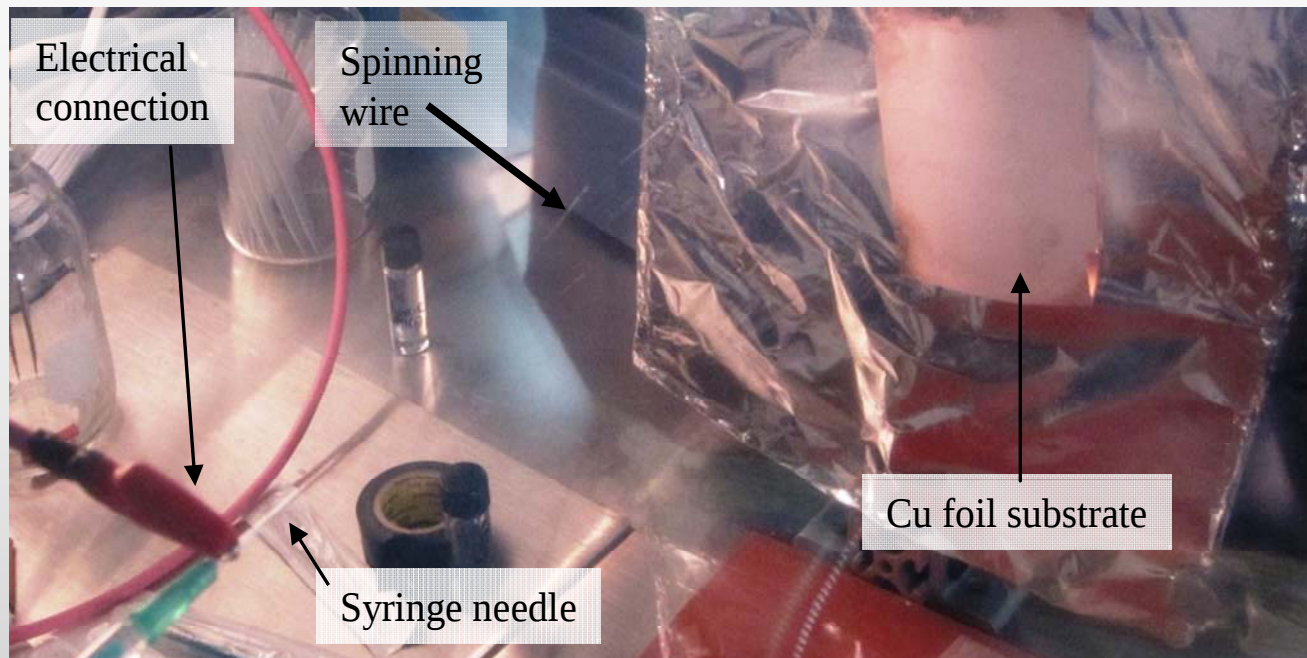
Low Magnification



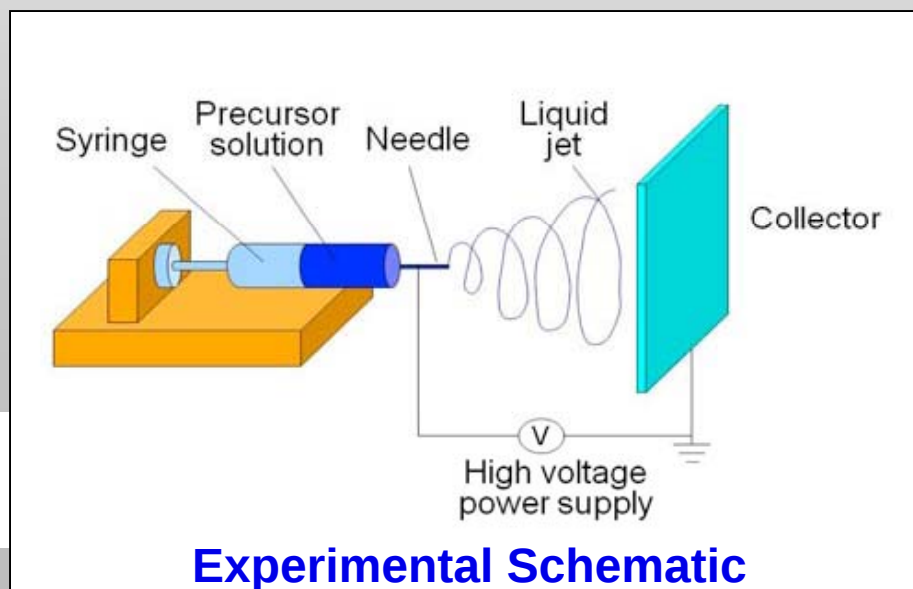
High Magnification



Electrospinning SiNWs from Si_6H_{12} -based Inks



SEM of 1st Nanowires

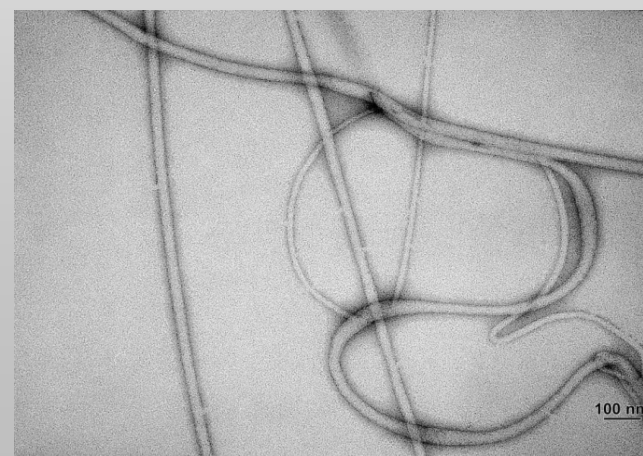
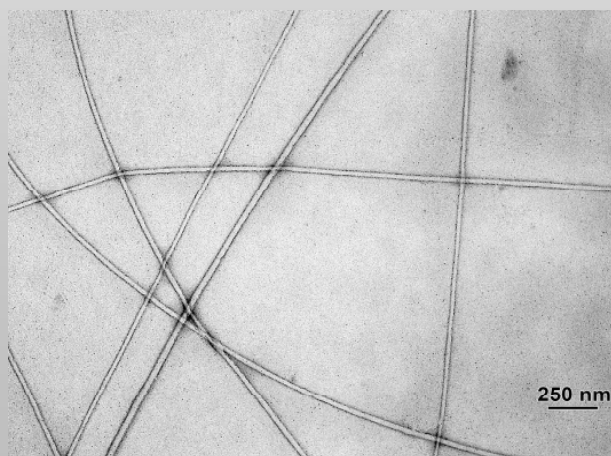
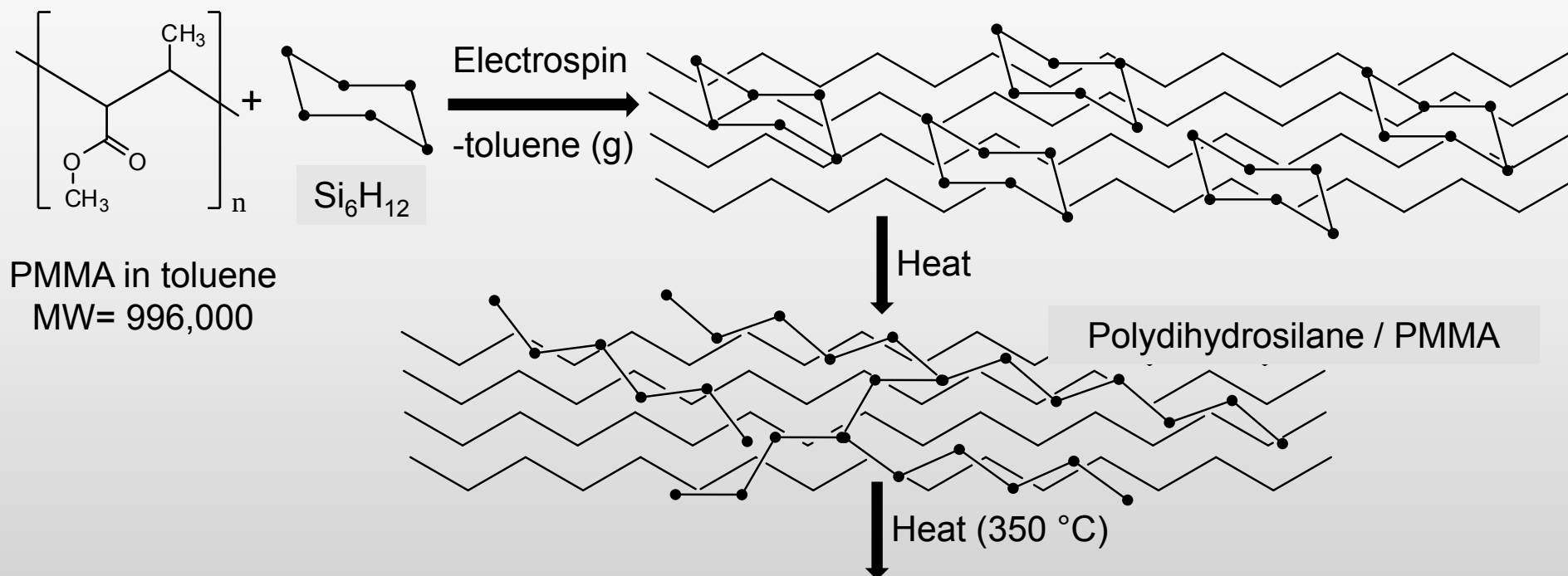


Experimental Schematic

Located inside
inert glovebox



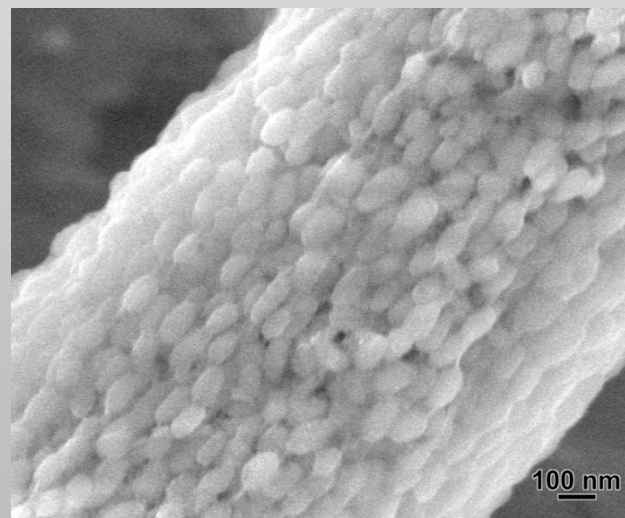
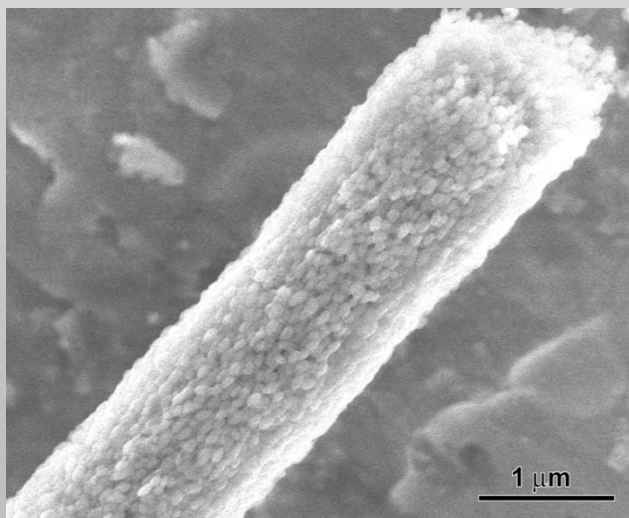
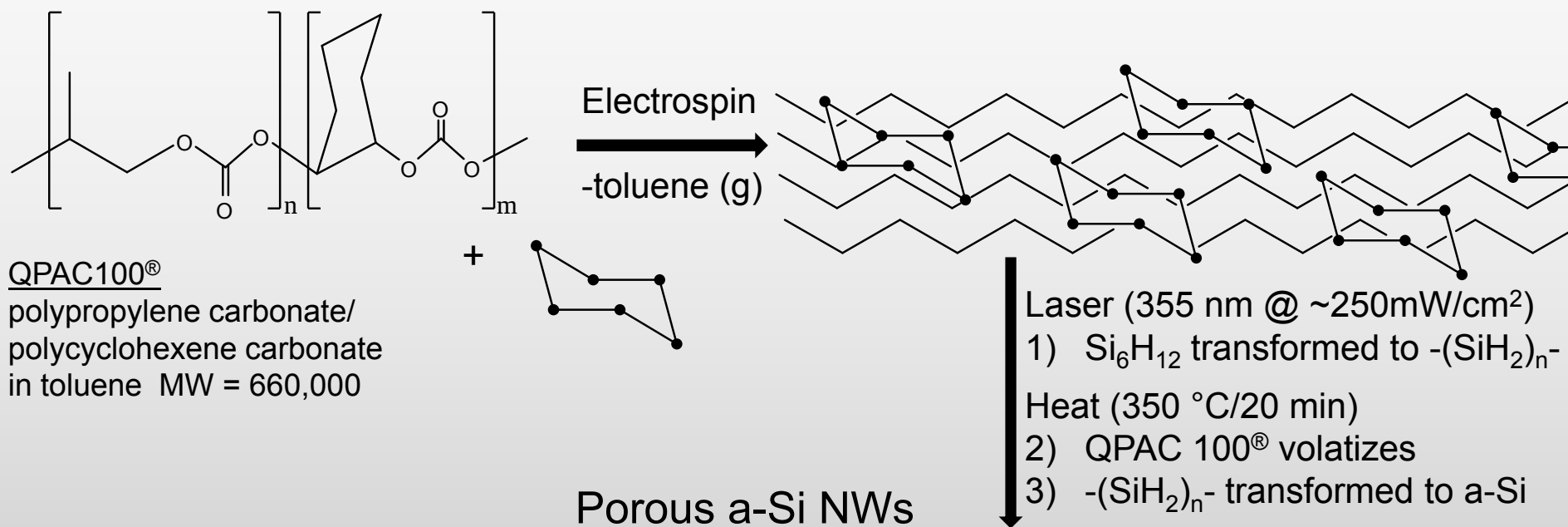
1st Gen Ink. PMMA in Toluene, Add Si₆H₁₂, Electrospin, Thermolysis



TEM micrographs



2nd Ink'. QPAC100[®]/Toluene/Si₆H₁₂, E-spin, Laser Treatment, Thermolysis

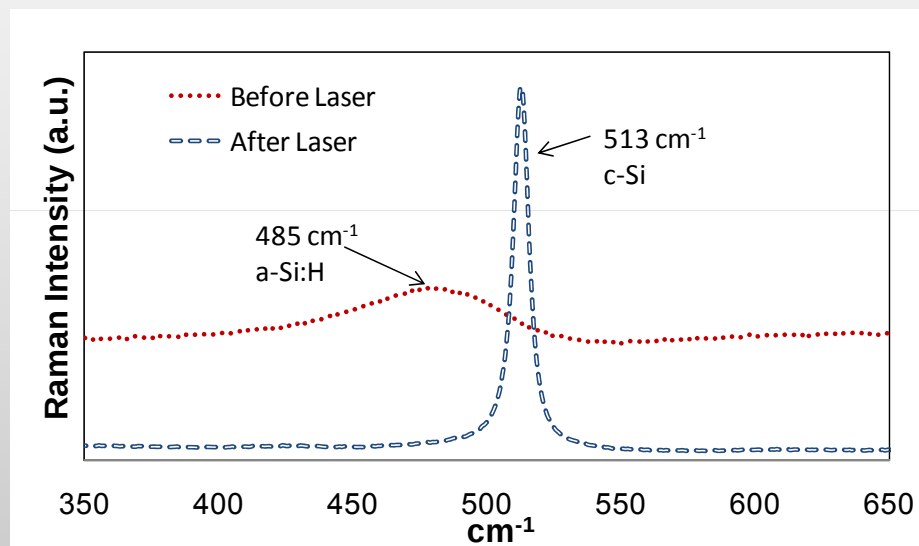


HRSEM micrographs



Characterization – Electrospun Si NWs from PMMA

Raman Spectra



before (red) and after (blue) melting

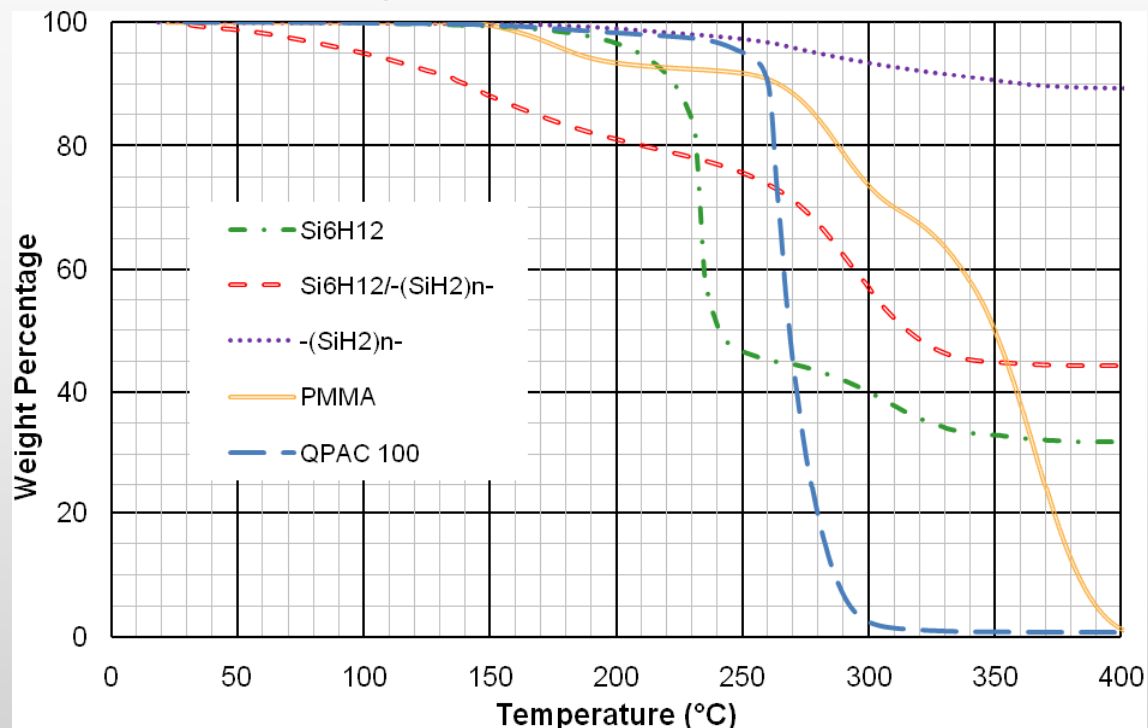
Optical Micrograph



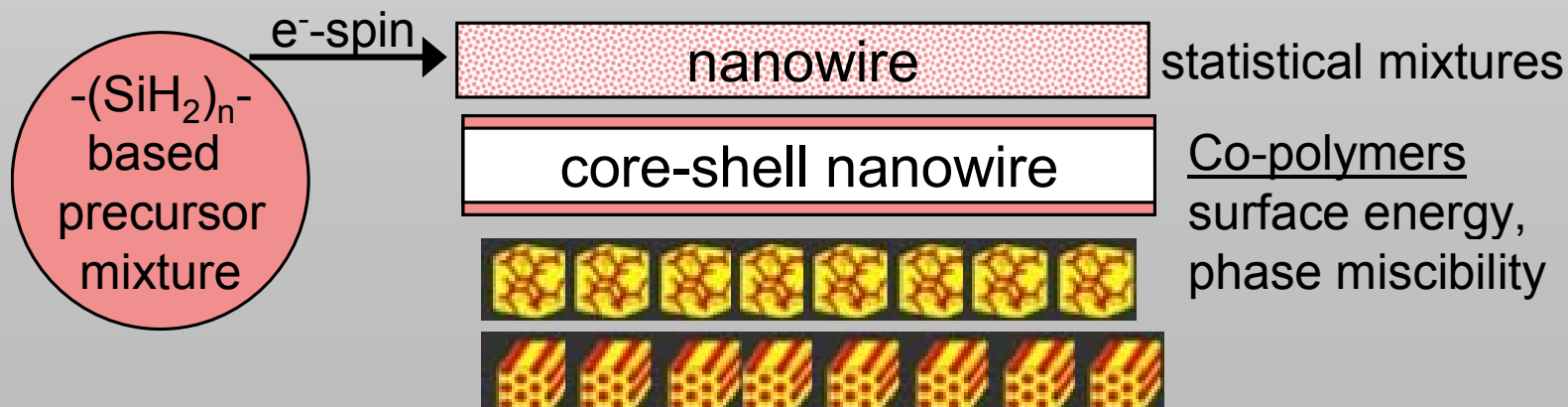
melted Si after focused beam



Electrospinning Polysilane-based Mixtures



Potential for New Copolymer Physical Chemistry



Future Plans

“Metallosilane” Solution Route to Metal Silicides (MSi_x)

Si_6H_{12} + metal reagent + solvent $\rightarrow$ viscous MSi_x inks

MSi_x inks $\rightarrow$ spin coating / electrospinning $\rightarrow$ thin films / nanowires

Applications of Si and MSi_x Films and Nanowires

Electroluminescence

Field emission

Lithium ion battery

anode

Photovoltaics

Sensors

Transistors

Thermoelectrics



Acknowledgements

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Nikko Toshogu Shrine

JustinH

KennyA



Sumo wrestling with
“John” Masuda in Kusastu



Masafumi Ogawa

Nikko-San Chuzen-Ji Temple

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